

Abstract of the Disclosure

5 An apparatus for transferring a container stored with a workpiece (for example, a semiconductor wafer container) between manufacturing stations includes: a manufacturing station that includes a generally horizontal support platform; one or more guides for guiding a vehicle; a vehicle configured to travel on one or more guides to a position below support platform; and a vertical translation
10 unit attached to one of the manufacturing station and the vehicle that vertically translates the container between a lowered position beneath the support platform and a raised position above the support platform. In this configuration, the apparatus can provide a relatively narrow work bay while still allowing sufficient room for a worker. Also, because the vehicle can operate below the level of the
15 manufacturing stations, there is no need for special mounting on the ceiling of the factory.